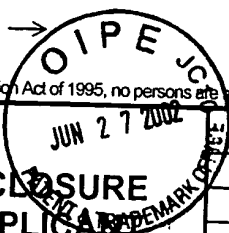


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Application Number	10/080,789
Filing Date	February 21, 2002
First Named Inventor	Staple, Bevan
Art Unit	2661
Examiner Name	Not Yet Known
Attorney Docket Number	019930-006100US

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ah	BC	AKIYAMA, TERUNOBU, et al., "Controlled Stepwise Motion in Polysilicon Microstructures," Journal of Microelectromechanical Systems, Vol. 2, No. 3, pp. 106-110, September 1993	
ah	BD	ASHRUF, C.M.A., et al., "Galvanic porous silicon formation without external contacts," Sensors and Actuators 74, pp. 118-122, 1999	
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ah	BN	KELLER, CHRISTOPHER GUILD, "Microfabricated Silicon High Aspect Ratio Flexures for In-Plane Motion," Dissertation, Fall 1998	

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